



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kiyoshi IRINO

Serial No.: 09/428,052

Filed: October 27, 1999

Group Art Unit: 2815

Examiner: J. Diaz

For: METHOD OF FABRICATING A SEMICONDUCTOR DEVICE CONTAINING NITROGEN IN A GATE OXIDE FILM (AS AMENDED)

PETITION FOR EXTENSION OF TIME

Director of Patents and Trademarks

Washington, D.C. 20231

July 7, 2000

Sir:

Applicants petition the Commissioner of Patents and Trademarks to extend the time for response to the Office Action dated March 9, 2000, for one-month from June 9, 2000, to July 9, 2000.

Attached please find a check in the amount of \$110.00 to cover the cost of the one month extension. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340. Two copies of this paper are enclosed herewith.

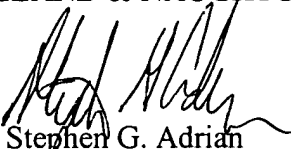
Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI,
McLELAND & NAUGHTON

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